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TITLE: PATTERN INSPECTING INSTRUMENT  
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ABSTRACT:

PURPOSE: To softly adapt the titled device to a pattern having many kinds of line widths by determining an optimum resolution by detecting the line width of a wiring pattern while making a resolution variable, and detecting a defect of a measured value corresponding to said resolution.

CONSTITUTION: The titled device is provided with measuring means 10; for executing a measuring operation in each radial direction by making a resolution variable, and a line width deciding means 13 for detecting the line width of a wiring pattern of every resolution obtained by said means, determining an optimum resolution and outputting the corresponding measured